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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/562,400 Confirmation No. : 8481
First Named Inventor : Hiroshi KANNAN
Filed : December 27, 2005
TC/A.U. : 1746
Examiner : N/A
Docket No. : 010986.57272US
Customer No. : 23911
Title : Plasma Generation Method, Cleaning Method, and
Substrate Processing Method

REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

On the attached copy of the Official Filing Receipt, it was noted that the city residence of inventor Hiroshi KANNAN and inventor Kazuya DOBASHI was incorrect. Inventor Hiroshi KANNAN is a resident of Hachioji-shi, JAPAN and inventor Kazuya DOBASHI is a resident of Yamanashi, JAPAN. Please make the appropriate changes to reflect the correct city residence of each inventor.

It was also noted that the title on the Official Filing Receipt was incorrect. Accordingly, please correct the title to read "Plasma Generation Method, Cleaning Method, and Substrate Processing Method."

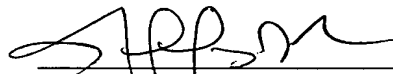
Also attached is a copy of the Application Data Sheet (which was previously submitted to the USPTO on December 27, 2005) reflecting the correct city residence and title of the application.

Kindly return the "Corrected" Official Filing Receipt to the undersigned attorney of record.

Please charge any additional fee or credit any overpayment to the Deposit Account of Crowell & Moring, L.L.P., Account No. 05-1323, Docket No.: 010986.57272US.

Respectfully submitted,

November 2, 2006



Jeffrey D. Sanok
Registration No. 32,169

CROWELL & MORING LLP
Intellectual Property Group
P.O. Box 14300
Washington, DC 20044-4300
Telephone No.: (202) 624-2500
Facsimile No.: (202) 628-8844
JDS:aw

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/562,400	04/25/2006	1746	4830	010986.57272US	16	76	8

CONFIRMATION NO. 8481

23911
CROWELL & MORING LLP
INTELLECTUAL PROPERTY GROUP
P.O. BOX 14300
WASHINGTON, DC 20044-4300

FILING RECEIPT



OC000000019472999

Date Mailed: 07/10/2006

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please mail to the Commissioner for Patents P.O. Box 1450 Alexandria Va 22313-1450. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Hachioji-shi
Hiroshi Kannan, ~~Tokyo~~, JAPAN;
Noboru Tamura, Yamanashi, JAPAN;
Kazuya Dobashi, ~~Tokyo~~, JAPAN;

Yamanashi

Assignment For Published Patent Application

TOKYO ELECTRON LIMITED, Tokyo, JAPAN

Power of Attorney: The patent practitioners associated with Customer Number 23911.

Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP04/09026 06/25/2004

Foreign Applications

JAPAN 2003-185160 06/27/2003

JAPAN 2003-185161 06/27/2003

If Required, Foreign Filing License Granted: 07/01/2006

The country code and number of your priority application, to be used for filing abroad under the Paris Convention, is **US10/562,400**

Projected Publication Date: 10/12/2006

Non-Publication Request: No

Early Publication Request: No

Title

Plasma Generation Method,
~~Method for generating plasma method for cleaning and method for treating substrate~~ Processing

Preliminary Class

134

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Since the rights granted by a U.S. patent extend only throughout the territory of the United States and have no effect in a foreign country, an inventor who wishes patent protection in another country must apply for a patent in a specific country or in regional patent offices. Applicants may wish to consider the filing of an international application under the Patent Cooperation Treaty (PCT). An international (PCT) application generally has the same effect as a regular national patent application in each PCT-member country. The PCT process **simplifies** the filing of patent applications on the same invention in member countries, but **does not result** in a grant of "an international patent" and does not eliminate the need of applicants to file additional documents and fees in countries where patent protection is desired.

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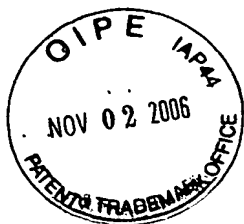
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APPLICATION DATA SHEET

APPLICATION INFORMATION

Application Number::	10/562,400
Filing Date::	December 27, 2005
Application type::	Regular
Subject Matter::	Utility
Title::	Plasma Generation Method, Cleaning Method, and Substrate Processing Method
Attorney Docket No.::	010986.57272US
Request for Early Publication?::	No
Request for Non-Publication?::	No
Suggested Drawing Figure::	1
Total Drawing Sheets::	16
Small Entity?::	No
Petition included?::	No

APPLICANT INFORMATION

Applicant one Authority Type::	Inventor
Primary Citizenship Country::	JAPAN
Status::	Full Capacity
Given name::	Hiroshi
Family name::	KANNAN
City of Residence::	Hachioji-Shi
Country of Residence	Japan
Street of mailing address::	1-54-1-204, Bessho
City of mailing address::	Hachioji-Shi
State or Province of mailing address::	Tokyo
Country of mailing address::	Japan
Postal or Zip Code of mailing address::	192-0363

Applicant two Authority Type::	Inventor
Primary Citizenship Country::	JAPAN
Status::	Full Capacity
Given name::	Noboru
Family name::	TAMURA
City of Residence::	Yamanashi
Country of Residence::	Japan
Street of mailing address::	1927-21, Ryuoshinmachi
City of mailing address::	Ryuo-Cho
State or Province of mailing address::	Nakakoma-Gun, Yamanashi
Country of mailing address::	Japan
Postal or Zip Code of mailing address::	400-0111

Applicant three Authority Type::	Inventor
Primary Citizenship Country::	JAPAN
Status::	Full Capacity
Given name::	Kazuya
Family name::	DOBASHI
City of Residence::	Yamanashi
Country of Residence::	Japan
Street of mailing address::	c/o TOKYO ELECTRON AT LIMITED, 650, Mitsuzawa
City of mailing address::	Hosaka-Cho, Nirasaki-Shi
State or Province of mailing address::	Yamanashi
Country of mailing address::	Japan
Postal or Zip Code of mailing address::	407-0192

CORRESPONDENCE INFORMATION

Correspondence customer number:: 23911

REPRESENTATIVE INFORMATION

Representative customer number:: 23911

DOMESTIC PRIORITY INFORMATION

Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This application	371 National Stage of	PCT/JP2004/009026	06/25/2004

FOREIGN PRIORITY INFORMATION

Country::	Application Number::	Filing Date::	Priority Claimed::
JP	2003-185160	06/27/2003	Yes
JP	2003-185161	06/27/2003	Yes

ASSIGNEE INFORMATION

Assignee Name:: TOKYO ELECTRON LIMITED
Street of mailing address:: 3-6 Akasaka 5-Chome
City of mailing address:: Minato-Ku
State or Province of Mailing Address:: Tokyo
Country of Mailing Address:: Japan
Postal or Zip Code of mailing address:: 107-8481